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AF-11763
RESPONSE UNDER 37 C.F.R. § 1.116
EXPEDITED PROCEDURE REQUESTED
EXAMINING GROUP 1763
PATENT

Customer No. 22,852

Attorney Docket No. 07553.0030

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
)
Kiichi HAMA et al.) Group Art Unit: 1763
)
Application No.: 09/478,370) Examiner: L. Alejandro Mulero
)
Filed: February 16, 2000)
) Mail Stop AF
For: PLASMA PROCESS APPARATUS)
)

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

AMENDMENT AFTER FINAL

In reply to the Final Office Action mailed August 13, 2003, and pursuant to
37 C.F.R. § 1.116, Applicants propose that this application be amended as follows:

AMENDMENTS TO THE CLAIMS:

Please cancel claims 1-8, 10-24, 26-36, 64-76, 78-84, 120-122, 124-126, 128-
137, and 166 without prejudice to or disclaimer of the subject matter recited therein.

Please amend claims 9, 25, 27 and 127 as follows:

9. (Amended) An apparatus for processing a process region of a substrate
using a plasma comprising:
a container substantially formed of a conductive material;

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